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Inventor: H. Montgomery Manning

Title: Support for Vertically Oriented Capacitors During the Formation of a Semiconductor Device

Assignee: Micron Technology, Inc.

Serial No.: 10/656,732

Filed: September 4, 2003 [RCE Filed Herewith]

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. Copies of all other cited art are attached. No admission is made regarding whether the listed references are prior art.


Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 12/20/05

By: 

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2608		SERIAL NO. 10/656,732	
 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: H. Montgomery Manning			
				FILING DATE Sept. 4, 2003 [RCE filed herewith]		GROUP 2812	
U.S. PATENT DOCUMENTS							
*Examiner's Initials	AA	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,617,222	09/03	Coursey			
	AB	2001/0012223	08/01	Kohyama			
	AC	2002/0030221	03/02	Sandhu et al.			
	AD	2002/0098654	07/02	Durcan et al.			
	AE	2002/0153614	10/02	Ema et al.			
	AF	2003/0178684	09/03	Nakamura			
	AG						
	AH						
	AI						
	AJ						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
	AK	2004/ 040252	12/04	PCT Search Report			Yes No
	AL						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AM		Kim, D. et al., "A Mechanically Enhanced Storage Node for Virtually Unlimited Height (MESH)				
			Capacitor Aiming at Sub 70nm DRAMs", IEEE Jan. 2004, pp. 3.4.1 – 3.4.4.				
	AN						
EXAMINER		DATE CONSIDERED					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							